

Electronic Patent Application Fee Transmittal				
Application Number:		10518371		
Filing Date:		28-Dec-2004		
Title of Invention:		PLASMA CHEMICAL VAPOR DEPOSITION METHOD AND PLASMA CHEMICAL VAPOR DEPOSITION DEVICE		
First Named Inventor/Applicant Name:		Hiroshi Mashima		
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Attorney Docket Number:		263787US2PCT		
Filed as Large Entity				
U.S. National Stage under 35 USC 371 Filing Fees				
Description	Fee Code	Quantity	Amount	Sub-Total in USD(\$)
Basic Filing:				
Pages:				
Claims:				
Miscellaneous-Filing:				
Petition:				
Patent-Appeals-and-Interference:				
Post-Allowance-and-Post-Issuance:				
Utility Appl issue fee	1501	1	1510	1510
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Description	Fee Code	Quantity	Amount	Sub-Total in USD(\$)
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Printed copy of patent - no color	8001	1	3	3
Total in USD (\$)				1813